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Substitute for form 1449B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)				Complete if Known	
				Application Number	10/599,106
				Filing Date	09/19/2006
				First Named Inventor	Ji Zhu
				Art Unit	2812
				Examiner Name	Unknown
Sheet	1	of	1	Attorney Docket Number	IB-1997

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		SONEK, ET AL., "Ultraviolet Grating Polarizers," Journal of Vacuum Science Technology, Vol. 19 (No. 4), p. 921-923, (August 17, 1981).	
		FLANDERS, ET AL., "Application of $\sim 100 \text{ \AA}$ Linewidth Structures Fabricated by Shadowing Techniques a)," Journal of Vacuum Science Technology, Vol. 19 (No. 4), p. 892-896, (November/December 1981).	
		CUI, ET AL., "Large Area 50 nm Period Grating by Multiple Nanoimprint Lithography and Spatial Frequency Doubling," Applied Physics Letters, Vol. 90, p. 043118-1-043118-3, (October 5, 2006).	
		FLANDERS, ET AL., "Generation of <50 nm Period Gratings Using Edge Defined Techniques," Journal of Vacuum Science & Technology B, Vol. 1 (No. 4), p. 1105-1108, (August 29, 1983).	
		JOHNSON, ET AL., "Generation of Surface Gratings with Periods < 1000 \AA ," Applied Physics Letters, Vol. 38 (No. 7), p. 532-534, (January 13, 1981).	
		Yu, ET AL., "Fabrication of Large Area 100 nm Pitch Grating by Spatial Frequency Doubling and Nanoimprint Lithography for Subwavelength Optical Applications," Journal of Vacuum Technology B, Vol. 19 (No. 6), p. 2816-2819, (August 6, 2001).	

Examiner Signature	/Allan Olsen/	Date Considered	12/15/2010
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached. This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /A.O./